

10/565879

1AP20 Rec'd PCT/PTO 23 JAN 2006

ATTORNEY DOCKET NO: 72096

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : TAKAMATSU
PCT No. : PCT/JP2004/009731
Confirm. No. : N/A
Filed : January 23, 2006
For : WAFER POLISHING METHOD
Art Unit : N/A
Examiner : N/A
Dated : January 23, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

The following references have been cited in the International Phase of the above-identified application.

- JP 2002-190458 discloses a water dispersion for chemical mechanical polishing. The reference has been cited under Category Y as being relevant to International claims 1, 4 and 7 - 17 and further cited under Category A as being relevant to International claims 2, 3, 5 and 6. No full translation is available at this time, however, attached is an English language abstract.

- JP 11-111657 discloses a polishing liquid and polishing method. The reference has been cited under Category Y as being relevant to International claims 1, 4 and 7 - 17 and further cited under Category A as being relevant to International claims 2, 3, 5 and 6. No full translation is available at this time, however, attached is an English language abstract.

- JP 63-74911 discloses a production of fine spherical silica. The reference has been

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cited under Category Y as being relevant to International claims 1, 4 and 7 - 17 and further cited under Category A as being relevant to International claims 2, 3, 5 and 6. No full translation is available at this time, however, attached is an English language abstract. Applicant further wishes to bring to the attention of the Examiner the corresponding U.S. Patent 4,842,837.

- JP 2002-252189 discloses a polishing liquid for semiconductor wafer. The reference has been cited under Category Y as being relevant to International claim 8. No full translation is available at this time, however, attached is an English language abstract.

Consideration of the above references is requested.

Respectfully submitted
for Applicant,

By:


John James McGlew
Registration No. 31,903
McGLEW AND TUTTLE, P.C.

JJM:tf
72096.5

Enclosed: PTO-1449 Form
copy of International Search Report
copies of (4) References

DATED: January 23, 2006
SCARBOROUGH STATION
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SHOULD ANY OTHER FEE BE REQUIRED, THE PATENT AND TRADEMARK OFFICE IS HEREBY REQUESTED TO CHARGE SUCH FEE TO OUR DEPOSIT ACCOUNT 13-0410.

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Form PTO-1449

U.S. Department of Commerce Sheet 1 of 1
Patent and Trademark OfficeLIST OF REFERENCES CITED
BY APPLICANT
(Use several sheets if necessary)Atty Docket No.: 72096
PCT No.: PCT/JP2004/009731
Applicant: TAKAMATSU

U.S. PATENT DOCUMENTS

Ex- aminer Initial	Document No.	Date	Name	Class	Sub- class	Filing Date
	<u>4,842,837</u>	<u>June 27, 1989</u>	<u>Shimizu et al.</u>			<u>Sept. 18, 1987</u>

FOREIGN PATENT DOCUMENTS

Ex- aminer Initial	Document No.	Date	Country	Class	Sub- class	Translation Yes/No
	<u>JP 2002-190458</u>	<u>July 5, 2002</u>	<u>Japan</u>			<u>No</u>
	<u>JP 11-111657</u>	<u>April 23, 1999</u>	<u>Japan</u>			<u>No</u>
	<u>JP 63-74911</u>	<u>April 5, 1988</u>	<u>Japan</u>			<u>No</u>
	<u>JP 2002-252189</u>	<u>Sept., 6, 2002</u>	<u>Japan</u>			<u>No</u>

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

Ex- aminer Initial	Author	Date	Title	Textbook in	Translation Yes/No

Examiner_____
Date Considered